MBE Under the Microscope: An Atomic-Scale View of "6.1 Å" III-V Semiconductor Surfaces and Interfaces*

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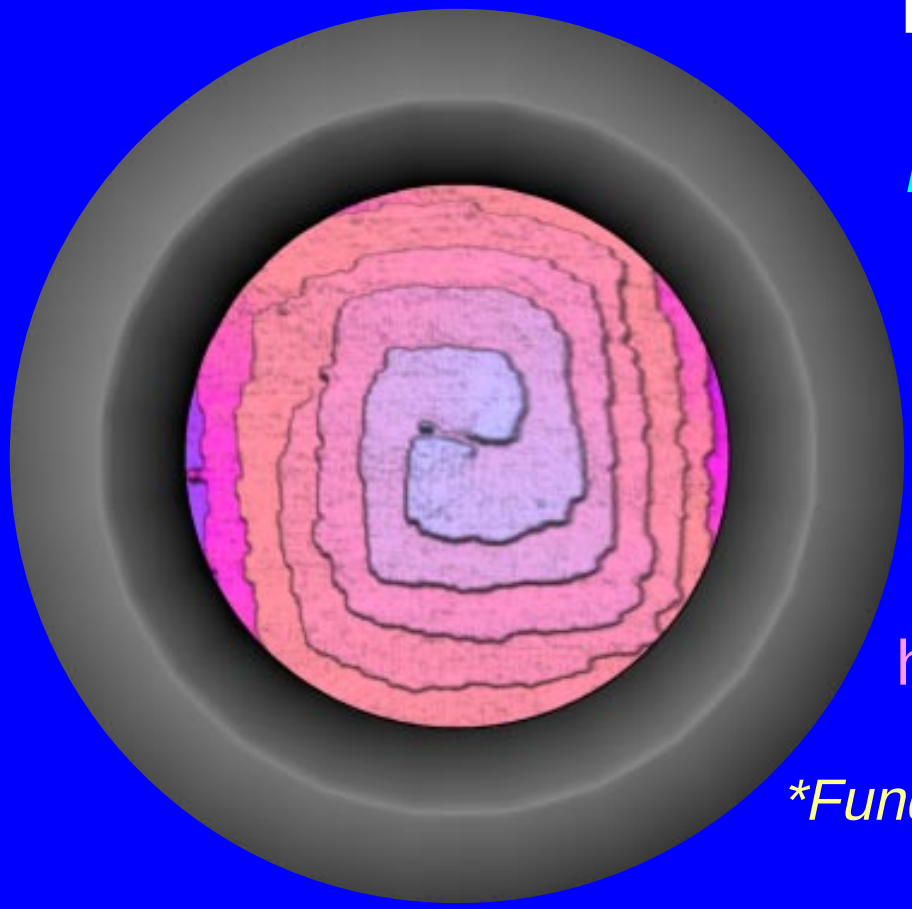
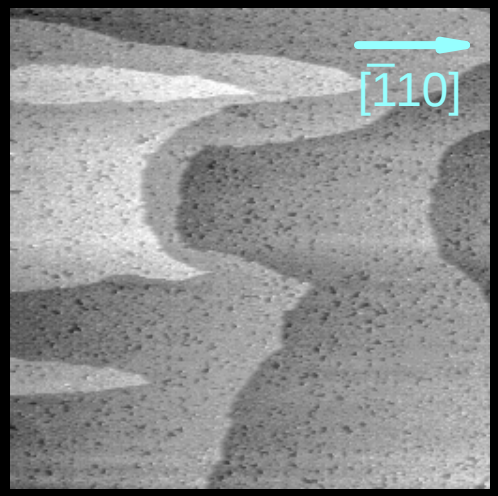


http://stm2.nrl.navy.mil/~lwhitman

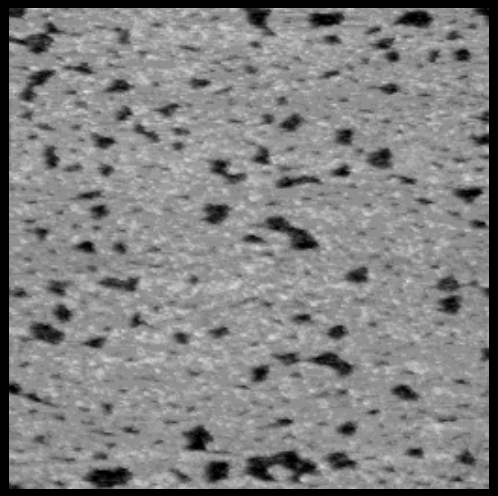
**Funded by the Office of Naval Research*

Can STM Help MBE?

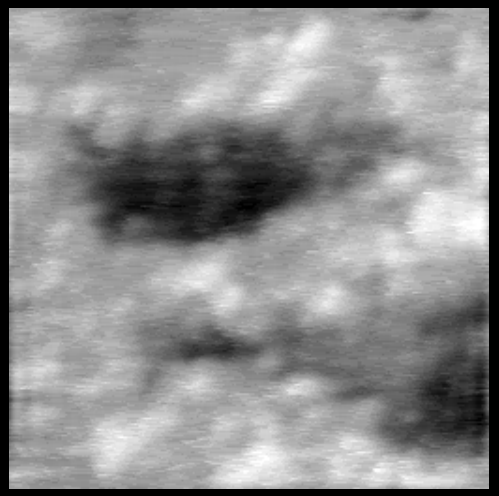
4/10/95: First images – "We'll grow our best GaAs(001)-(2×4)"



1.6 µm × 1.6 µm

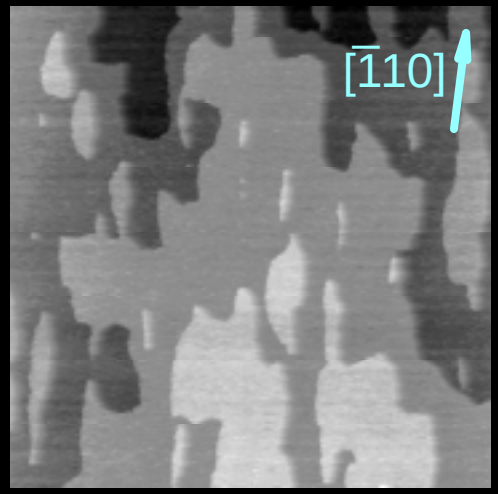


4000 Å × 4000 Å



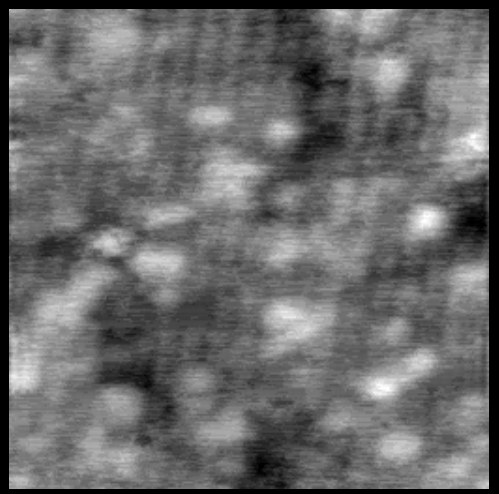
320 Å × 320 Å

NEXT DAY: big pits gone, atomic-scale order visible



1.6 µm × 1.6 µm

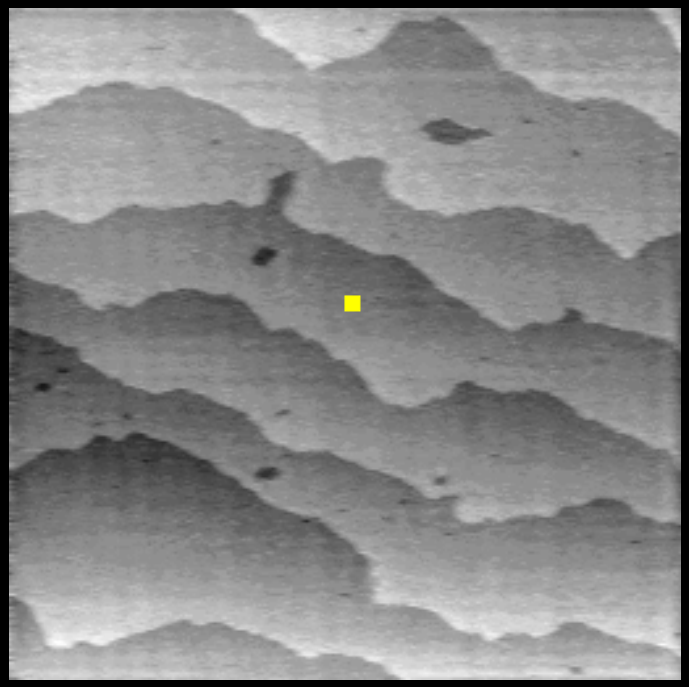
4000 Å × 4000 Å



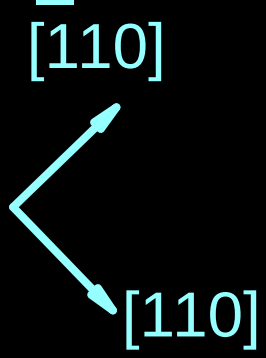
320 Å × 320 Å

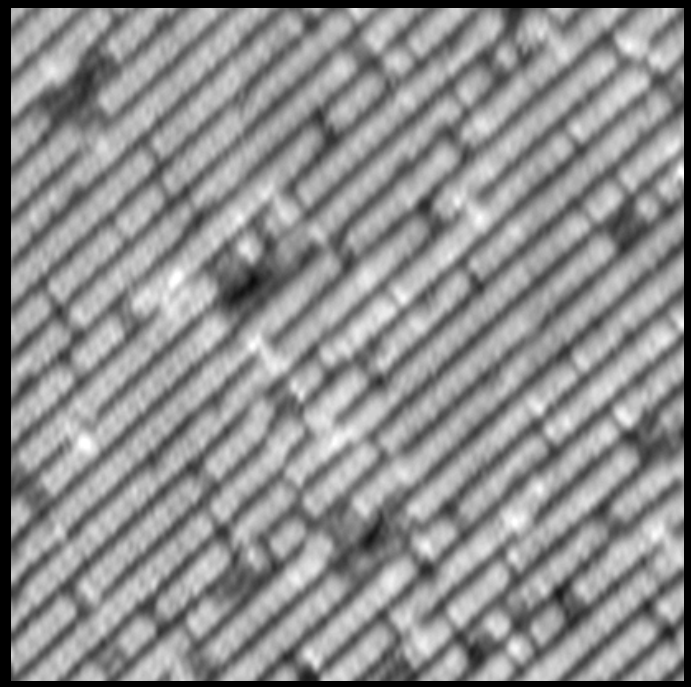
After Two Years of STM/MBE

5/97: Almost ideal terrace morphology, good (2×4)



1.6 µm × 1.6 µm





320 Å × 320 Å

MBE: 1 ML/s at 600 °C, with 30 s interrupts every 90 s.
After ~1 µm, 10 min interrupt to finish.

Cast of Characters

From NRL:

W. Barvosa-Carter

B. R. Bennett

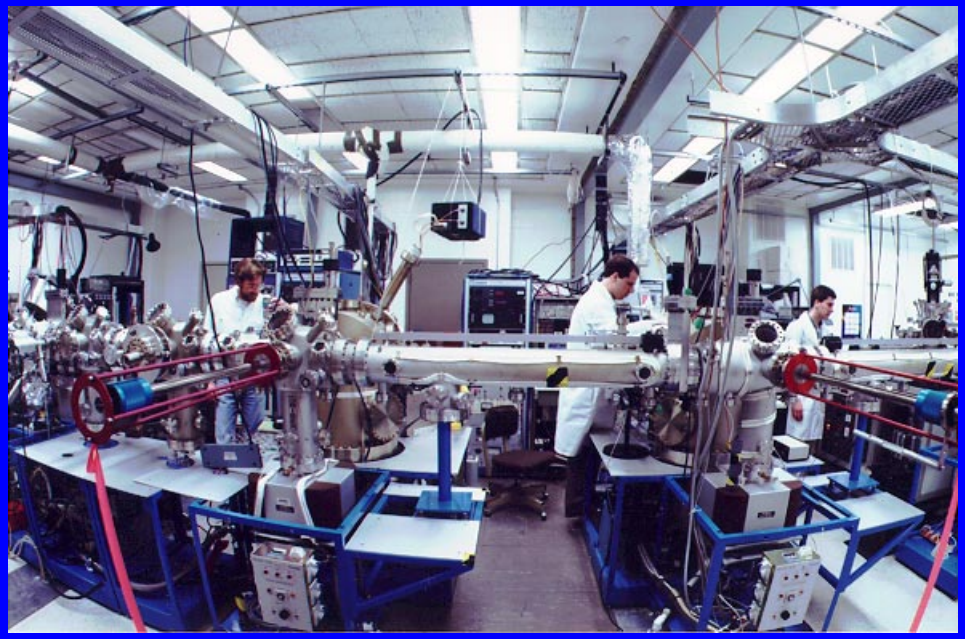
S. C. Erwin

B. V. Shanabrook

M. E. Twigg

M.-J. Yang

NRL Code 6000 Epicenter



From Elsewhere:

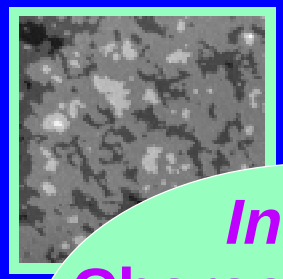
B. Z. Nosho and W. H. Weinberg, UCSB

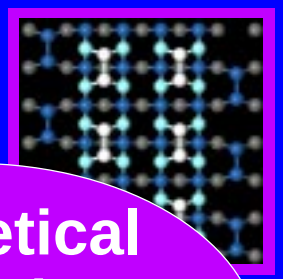
P. M. Thibado, U. Arkansas

M. B. Weimer, Texas A&M

J. J Zinck, HRL

III-V Device Optimization





In-Situ Characterization

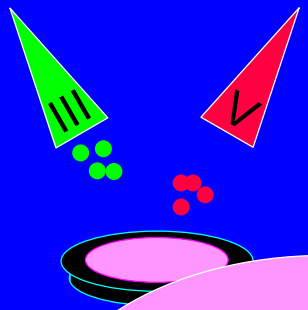
RHEED, XPS, STM

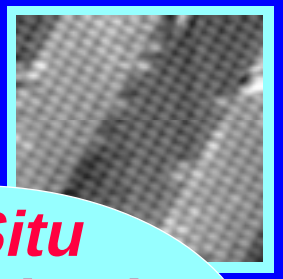
Theoretical Calculations

LDA, Modeling

Device Performance

Electrical
Optical





MBE Growth

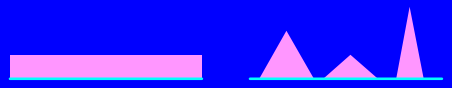
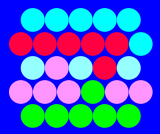
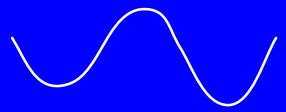
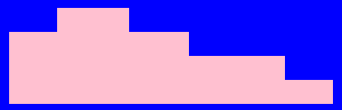
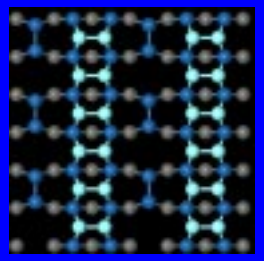
Temperature
Flux Rates
Interrupts

Ex-Situ Characterization

X-STM X-ray
X-TEM Raman

Requires integrated approach.

What Do We Need To Learn?

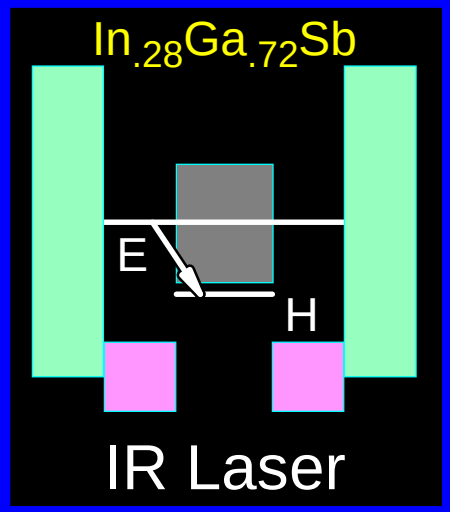
- Interface roughness – two components
  - Topography: 2D vs 3D growth 
  - Intermixing: during or after interface formation 
- Kinetics vs. Thermodynamics 
  - Interplay between energy *barriers* and energy *differences*
- Continuum vs. Atomistic 
  - Island/Step edge dynamics
  - Surface reconstruction: anisotropy, III/V stoichiometry 

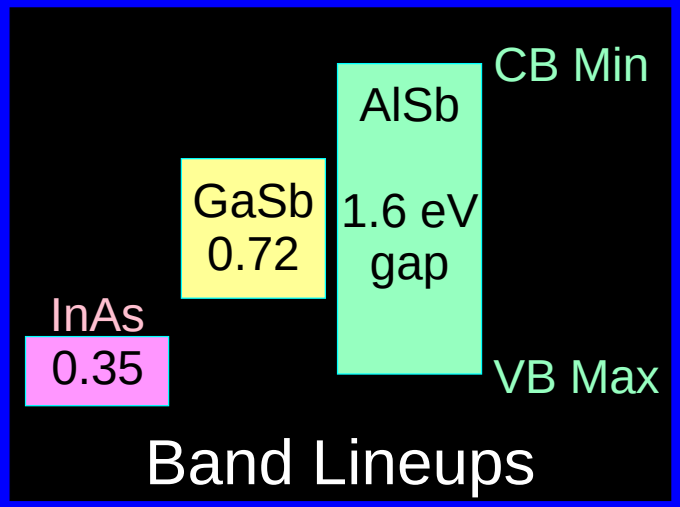
Control via growth methods, e.g. MEE, interrupts.

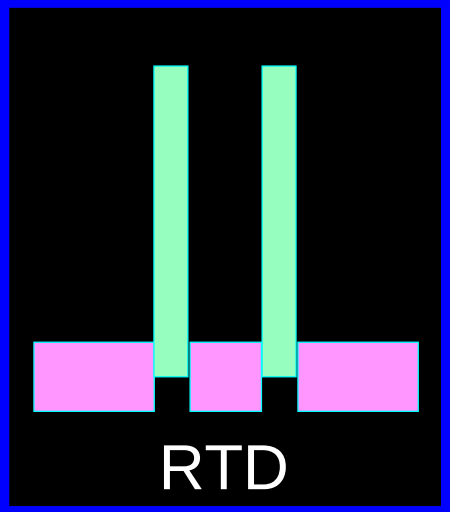
"6.1 Å" Family of III-V's: InAs, GaSb, AlSb

6.06 Å 6.10 Å 6.14 Å

- For high-speed and optoelectronic devices
  - Resonant tunneling diodes (RTD's), IR detectors, IR lasers
- Composed of superlattices and quantum-wells
  - Interfaces critical: large volume fraction of device







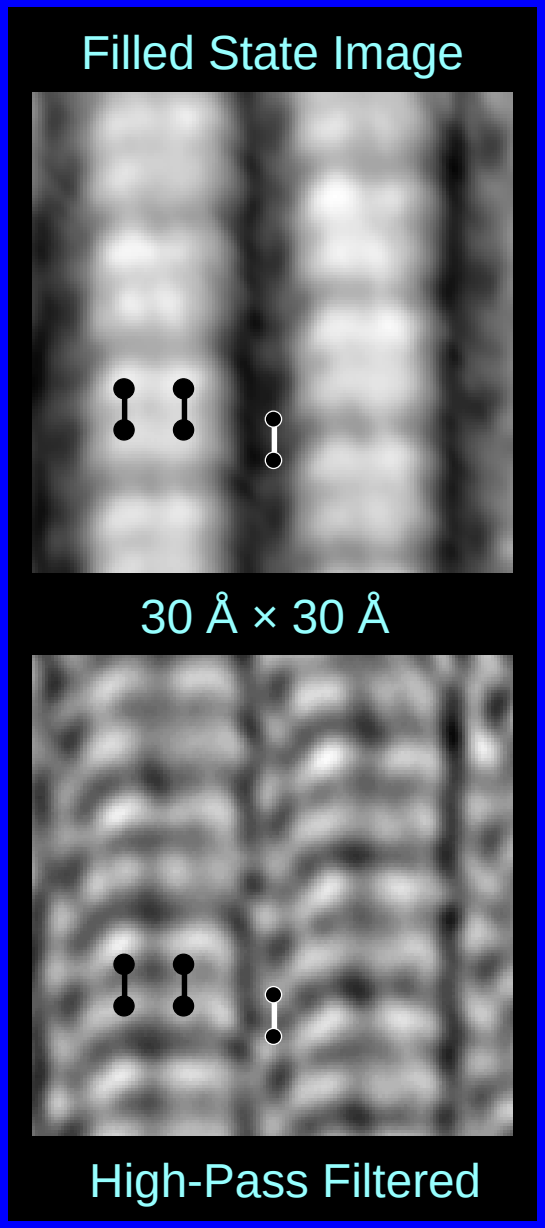
Properties sensitive to sub-ML interface variations.

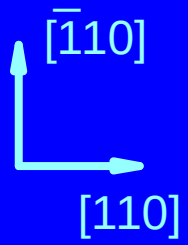
Start At The Atom: Surface Reconstructions

- Focus on device-growth conditions: ***V-rich***
- InAs(001)-(2×4), c(4×4): like GaAs
  - Nominally obeys ***Electron Counting Model*** (ECM): *In-dangling bonds (db's) empty, As-db's filled*
- AlSb vs. GaSb(001): role of material properties vs. lattice constant (AlSb 0.7% larger)
  - AlSb: only (1×3), c(2×6) RHEED reports
  - GaSb: (1×3), c(2×6), (1×5), (2×5) by RHEED, previous STM of c(2×6)

InAs(001)-(2×4) Reconstruction

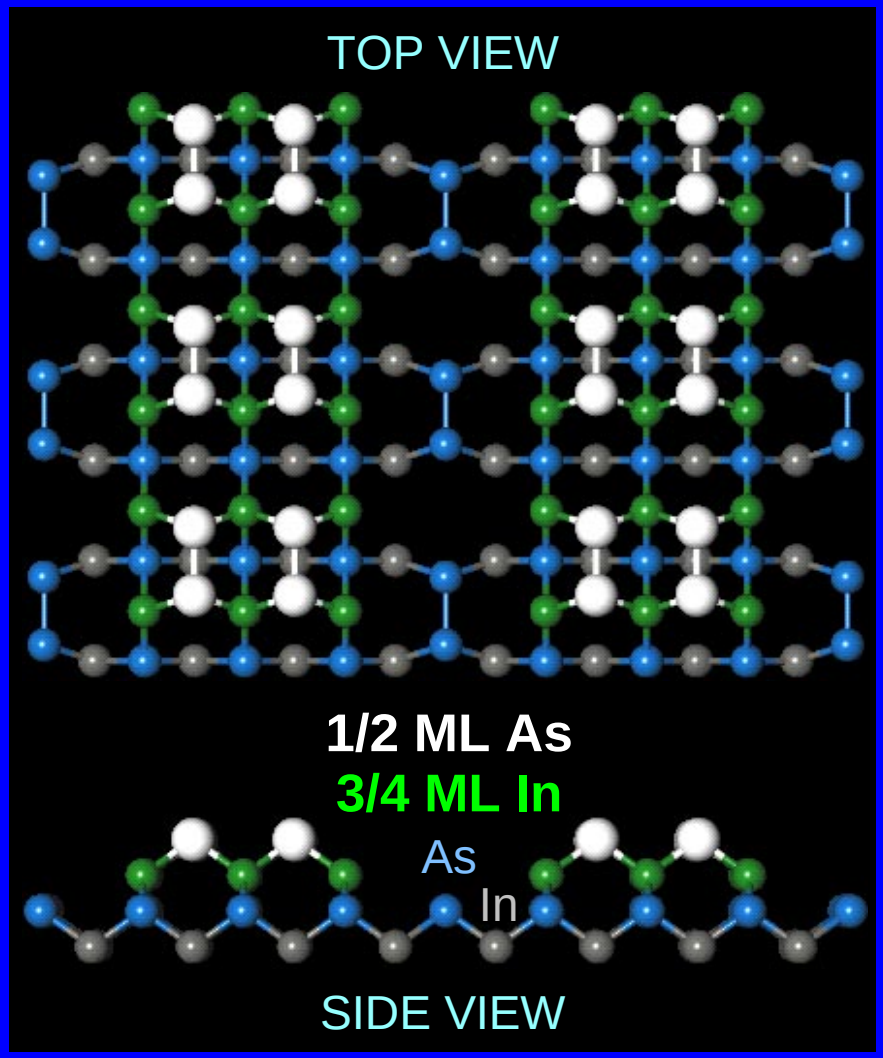
GaAs(001)-"(2×4)"





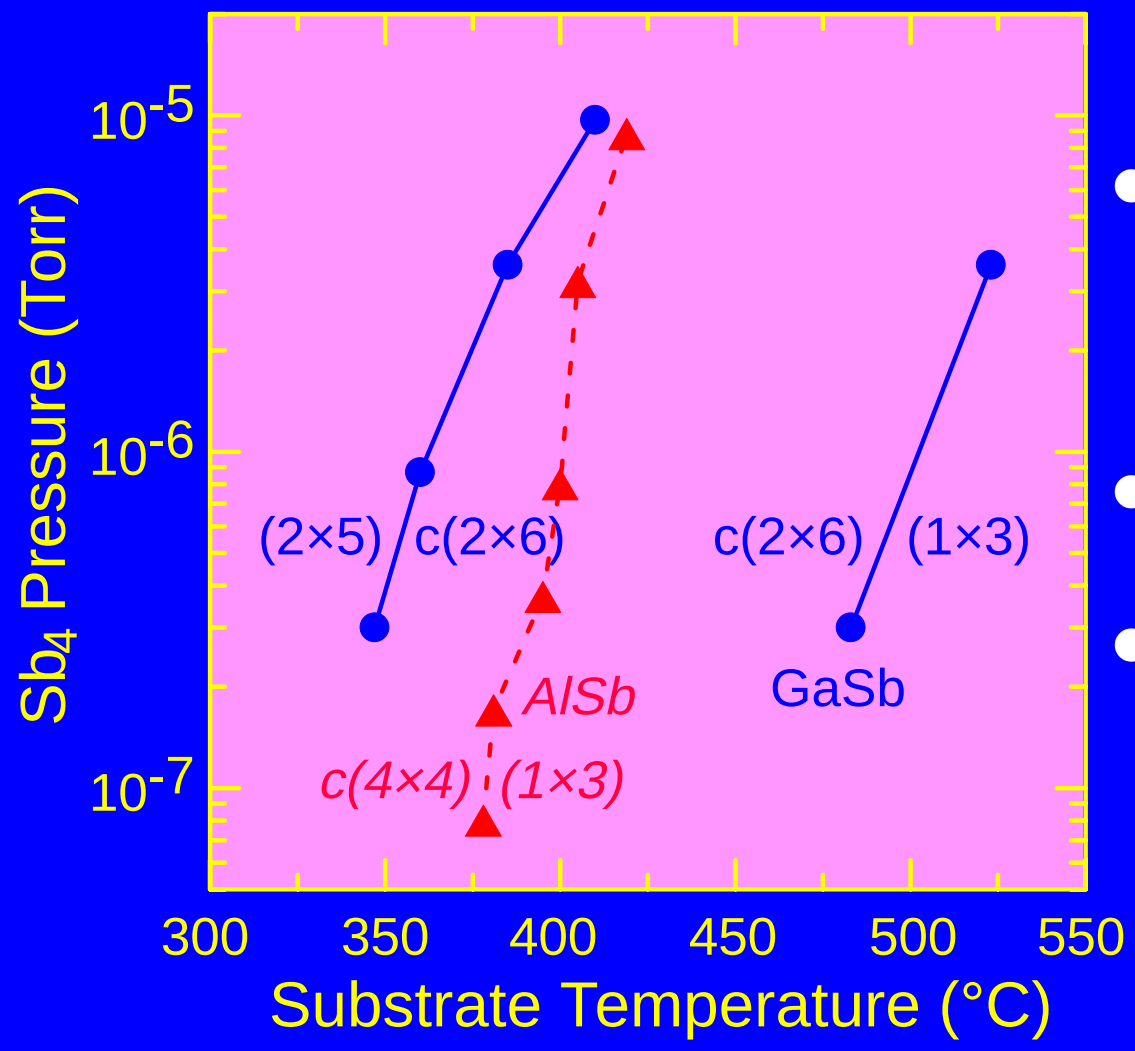
0.5 ML As
on
0.75 ML In

III-V(001)-β2(2×4)



Follows electon counting model.

GaSb-AlSb RHEED Structure Diagram

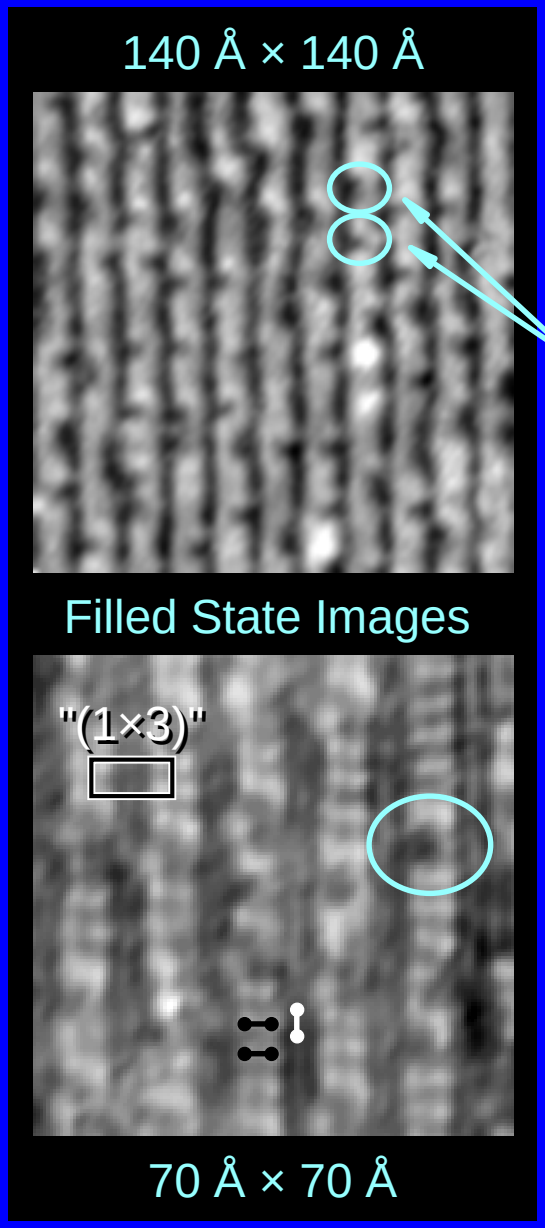


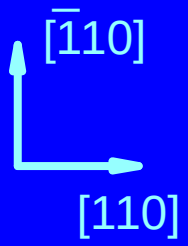
- GaSb: (1×3) - c(2×6) - (2×5): under optimal conditions no (1×5)
- AlSb: (1×3) - c(4×4)
- AlSb(001)-c(4×4) for first time

What are structures, what makes them different?

III-Sb(001)-"(1×3)" Reconstruction

GaSb(001)-c(2×6)

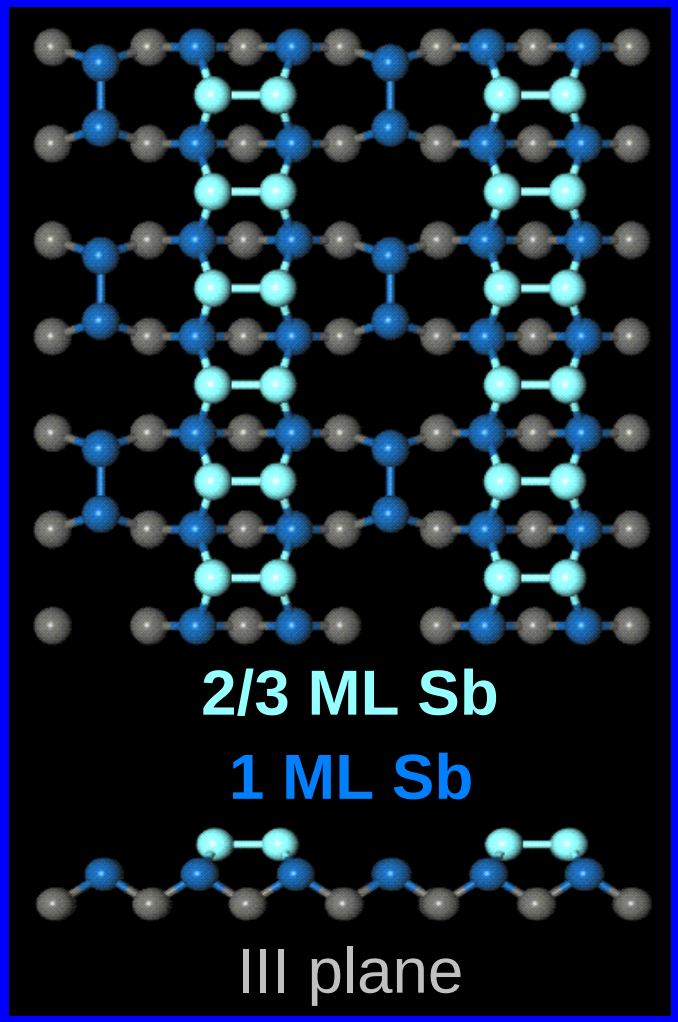




Quasi-periodic defects

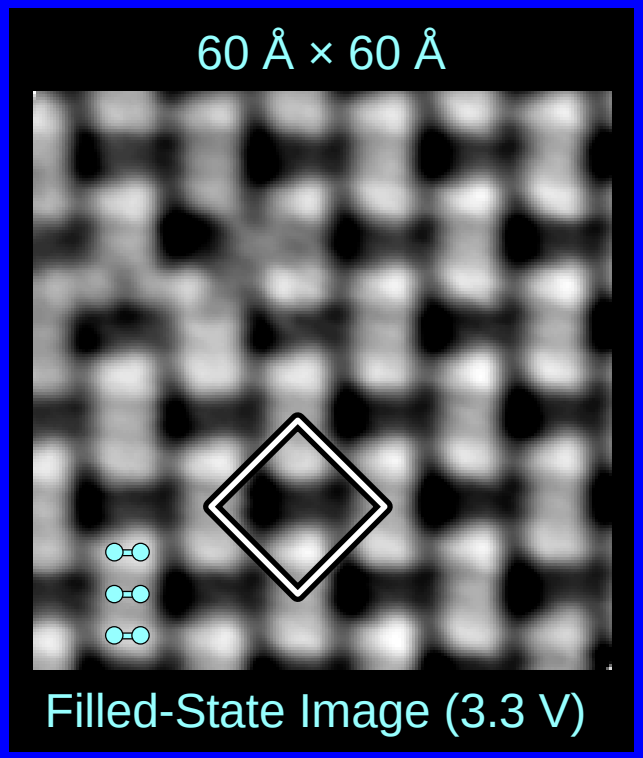
1.66 ML Surface Sb

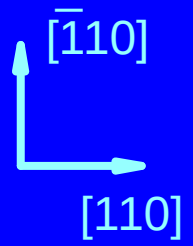
III-Sb(001)-c(2×6)



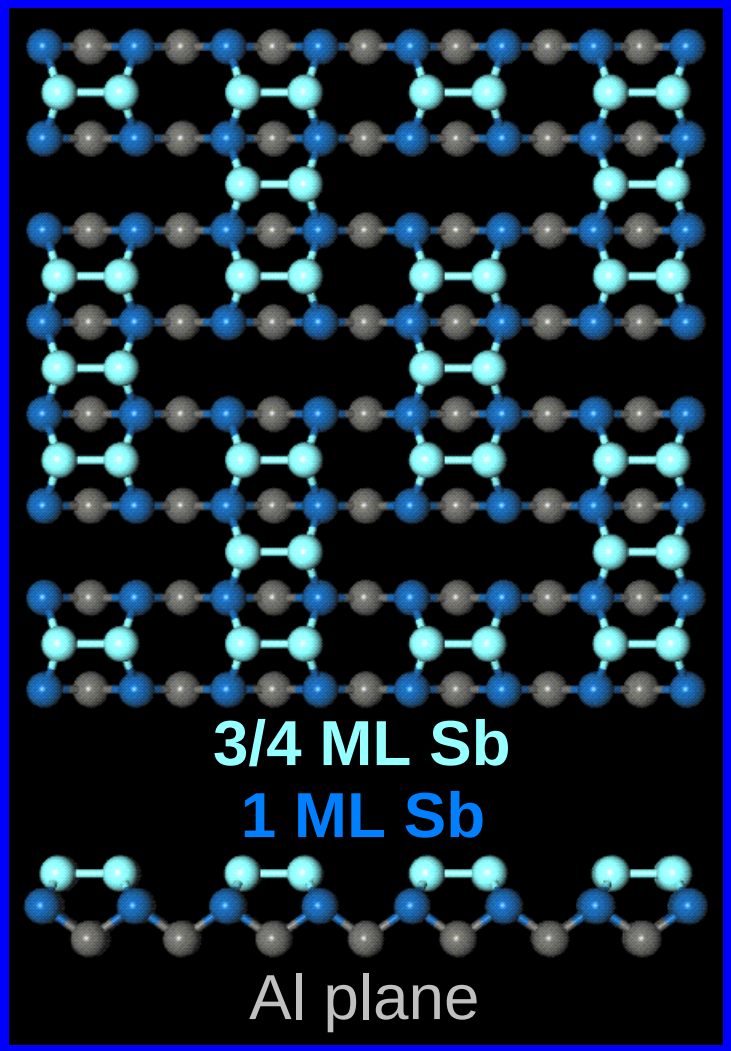
(Al,Ga,In)Sb "(1×3)" all look similar.
Actual structure more complex?

AlSb(001)-c(4×4) Reconstruction





1.75 ML Surface Sb

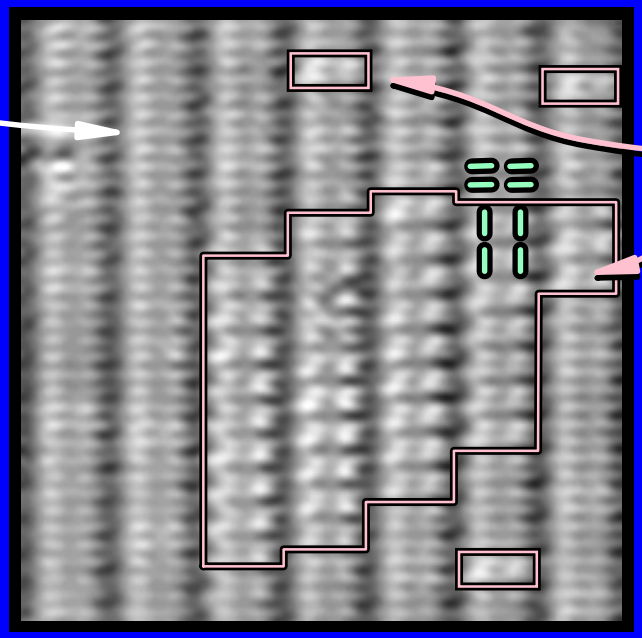


Simple dimer row structure: like ***all other*** III-V's (except GaSb).

Follows ECM: expect insulating surface.

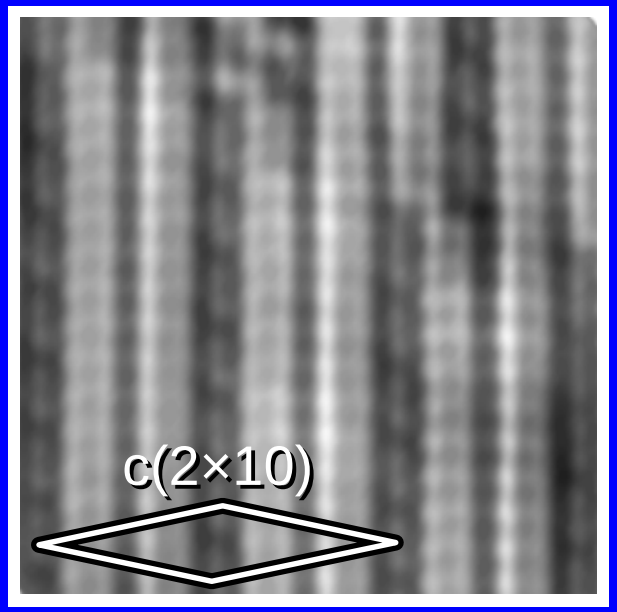
GaSb(001)-"(2×5)" Reconstructions: STM

Two (*n*×5)-like structures
(atypical mixed-phase shown)



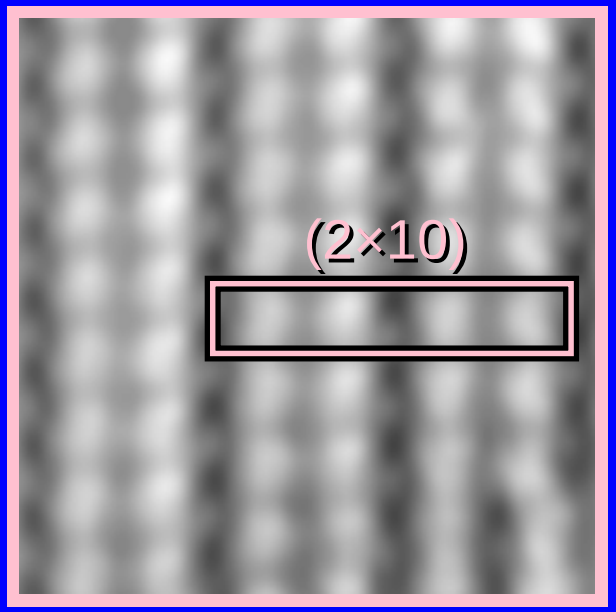
150 Å: Filled States (2.4 V)

On high-T side of
"×5" range, c(2×10)

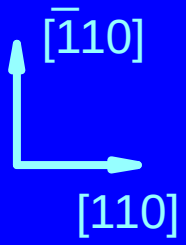


65 Å: Filled States (1.8 V)

At lower T's,
different (2×10):
features rotate,
are ~1 Å higher
than on c(2×10)

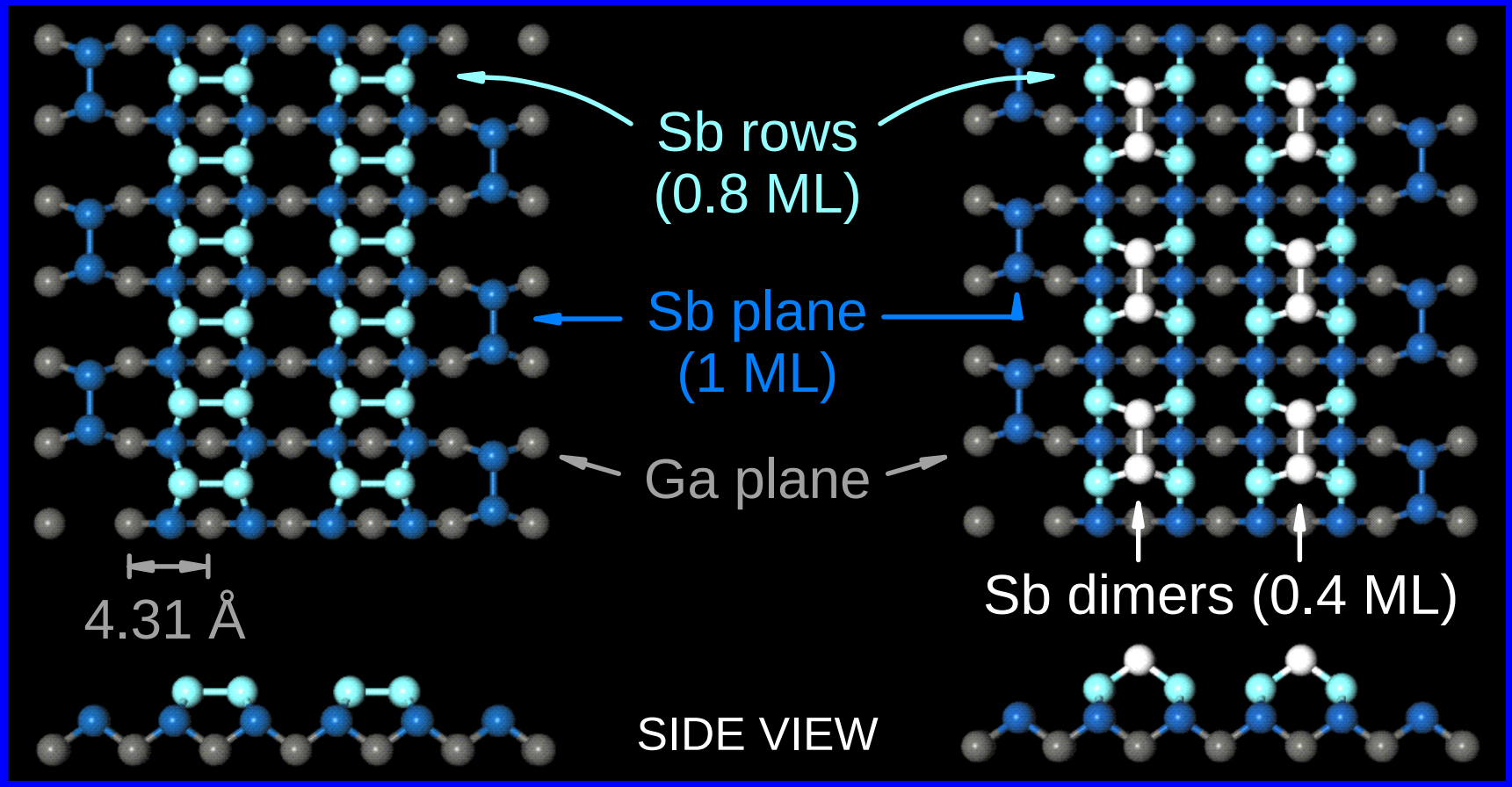


65 Å: Filled States (0.4 V)



GaSb(001)-"(2×5)" Models

c(2×10): **1.8 ML Sb** (2×10): **2.2 ML Sb**



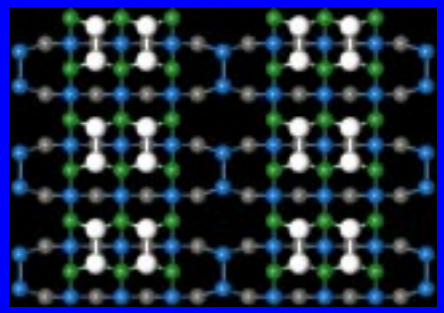
Three extra *e*'s/(2×5): **expect metallic surfaces**.

Both models violate electron counting model!

"6.1 Å" V-Terminated Reconstructions

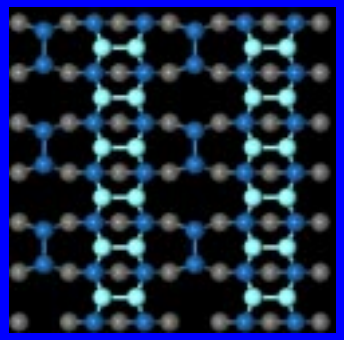
InAs		AlSb	GaSb	
c(4×4)	1.75 As/1.0 In	c(4×4)	(2×10)	2.20 Sb/1.0 Ga
(2×4)	0.5 As/0.75 In		c(2×10)	1.80 Sb/1.0 Ga
		c(2×6)	c(2×6)	1.66 Sb/1.0 Ga

- GaSb (2×10)'s violate ECM – weakly metallic



(2×4)

InAs ← *Growth Surfaces* → GaSb / AlSb

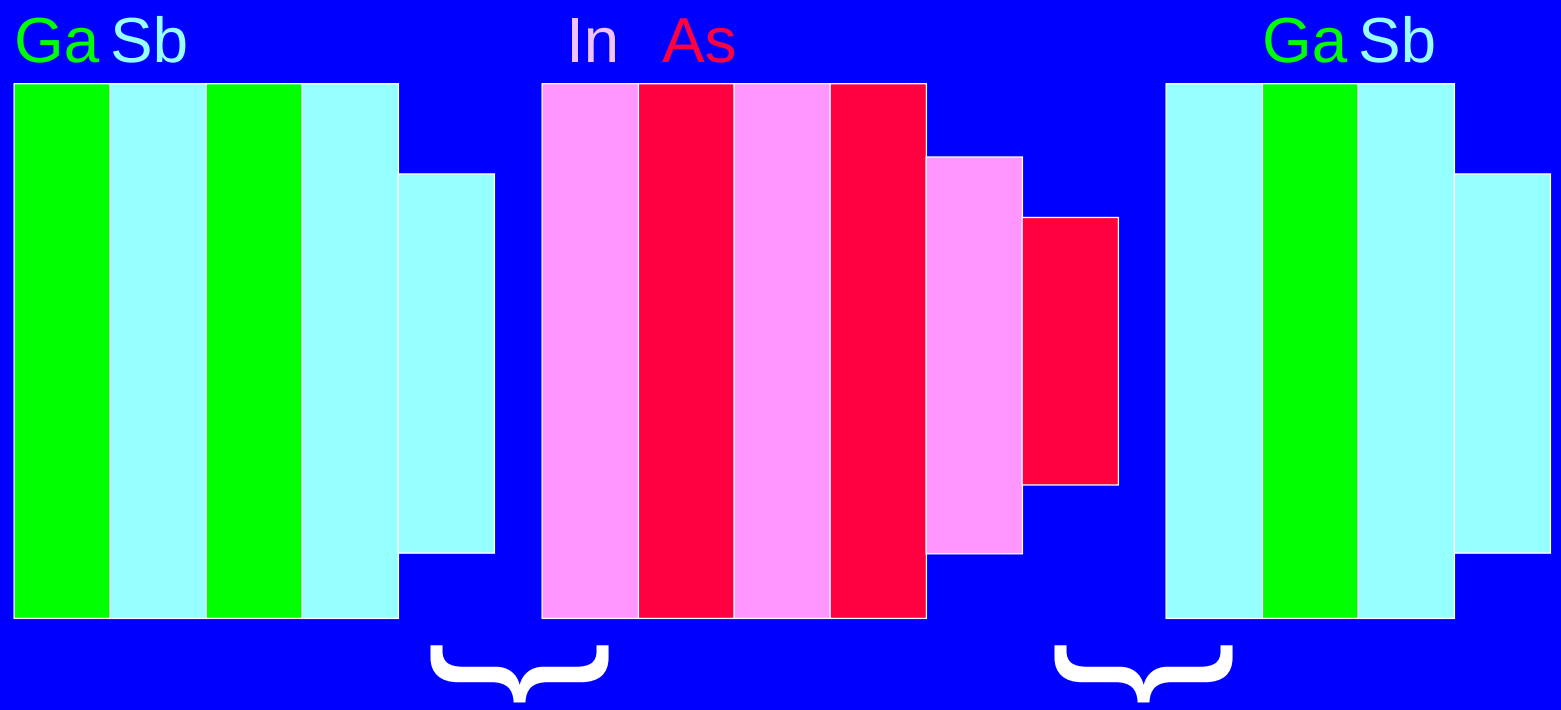


c(2×6)

Do reconstructions impact devices?

Impact of Reconstruction on III-V Heterostructure Interfaces: GaSb/InAs

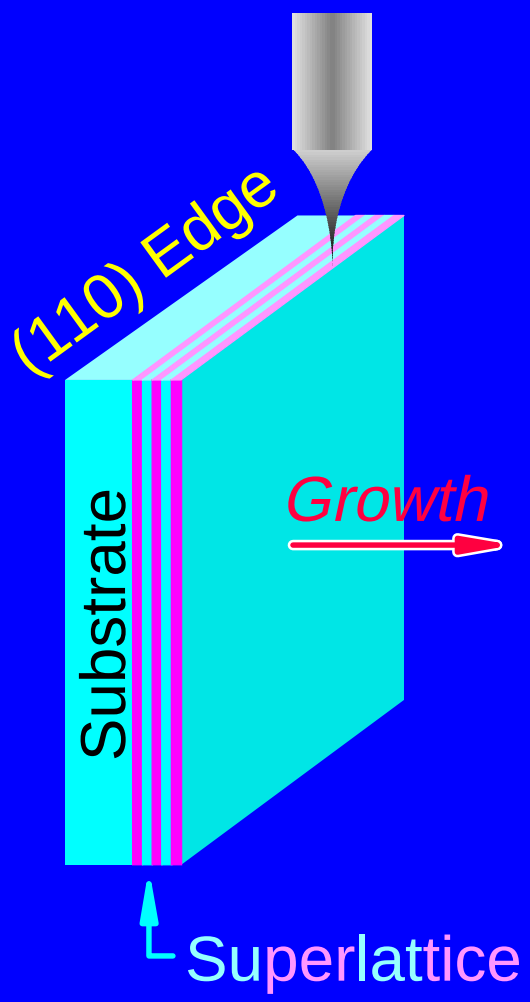
MBE Growth Direction →



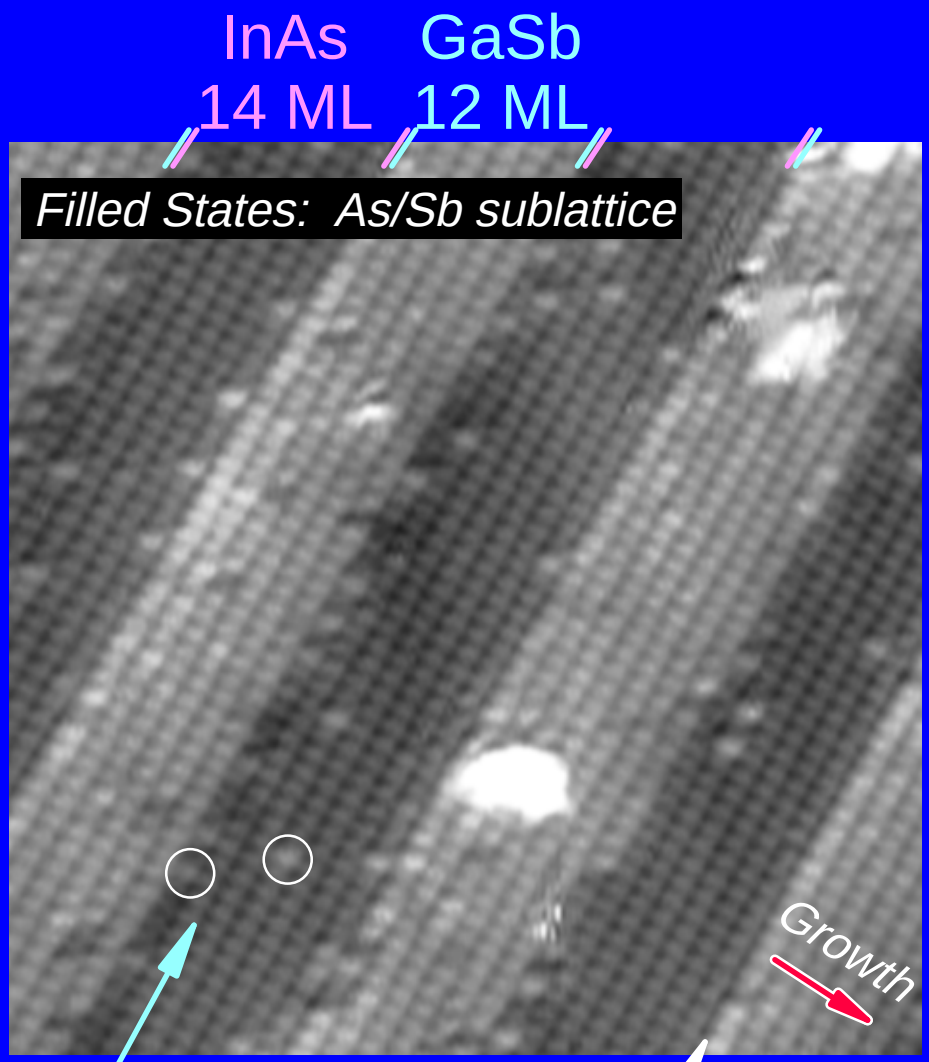
GaSb(001)-c(2×6)
Excess Sb on growth surface (1.66 layers) =>
intermixing at interface?

InAs(001)-(2×4)
As deficient on growth surface (0.5 layers) =>
intermixing at interface?

X-STM of GaSb/InAs Superlattice



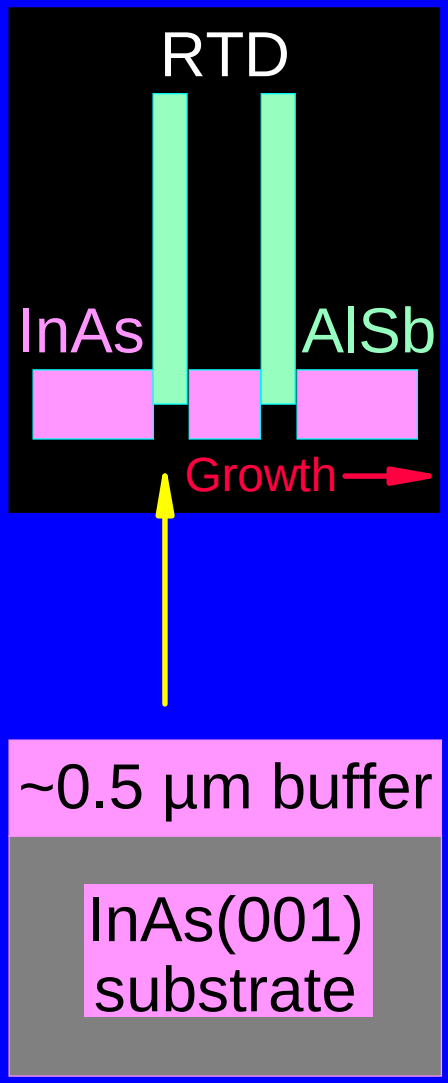
X-STM images **alternate** layers.



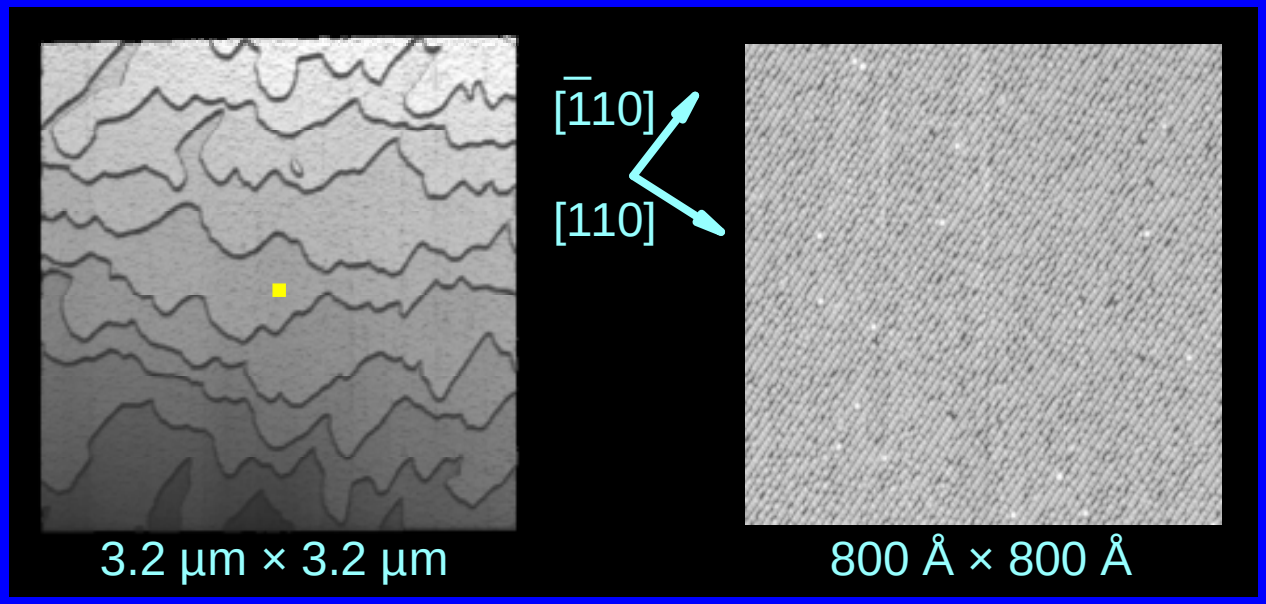
Excess Sb in InAs

GaSb/InAs ≤2 ML

Evolution of InAs/AlSb/InAs RTD Interfaces

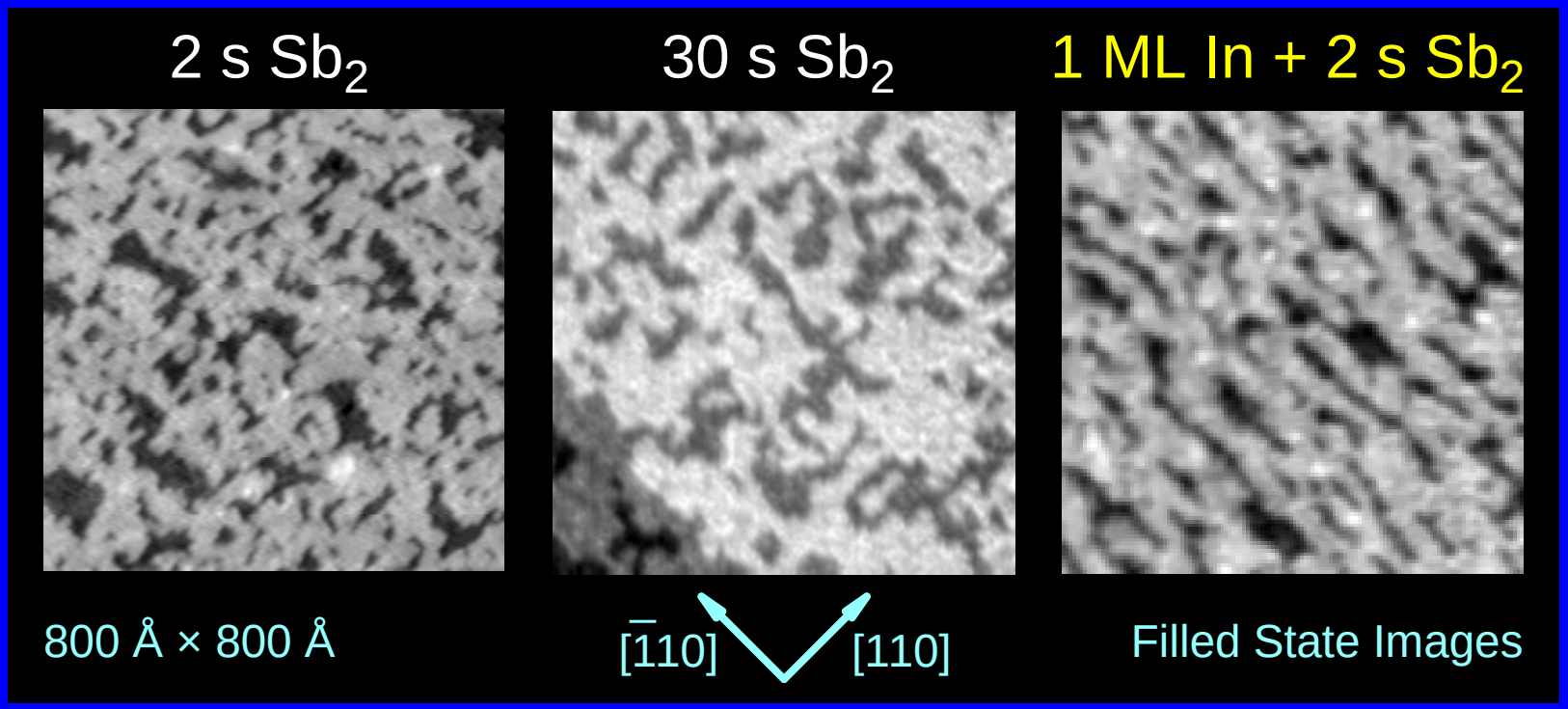


InAs(001)-(2×4) Buffer Layer

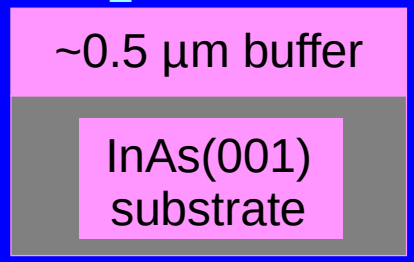


- Nearly ideal surface
- ~1 µm-wide terraces => 0.05° miscut
- MBE: 1 ML/s at 500 °C, 30 s interrupts every 90s, 10 min interrupt after ~1 µm

Sb_2 on InAs(001)-(2×4) at ~400 °C



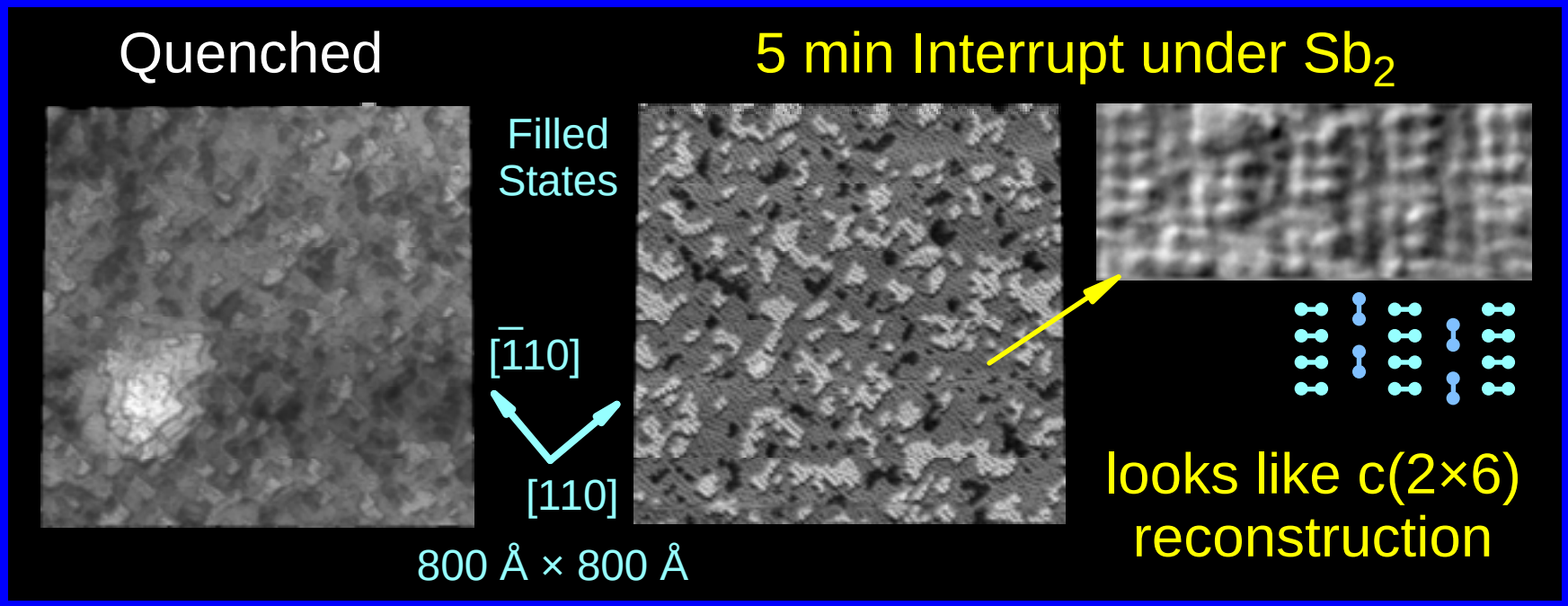
Sb_2 Interrupt

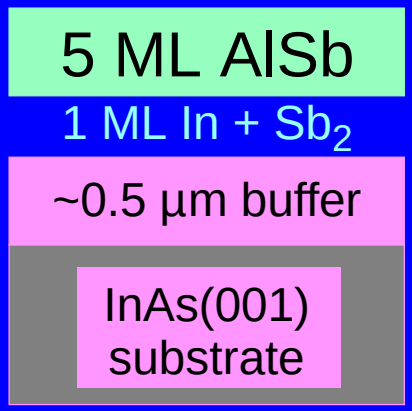


- Want InSb-like bonds at interface
- Surface has InSb "(1×3)"-like reconstruction

Sb very reactive: creates 2-level surface with 25% vacancy islands.

5 ML AlSb on InAs at ~400 °C

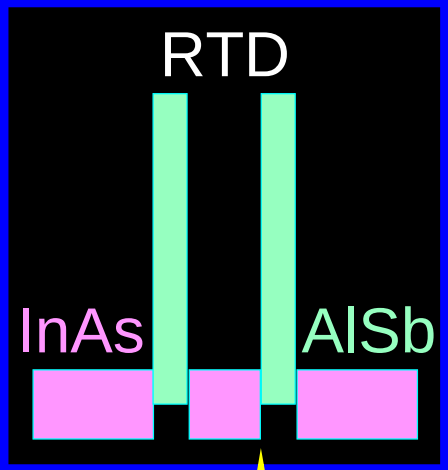




- Addition of AlSb epilayer roughens surface to 3 levels

Interrupt required for well-defined islands and atomic-scale order.

22 ML InAs on AlSb/InAs at ~400 °C



30 s Sb_2

22 ML InAs

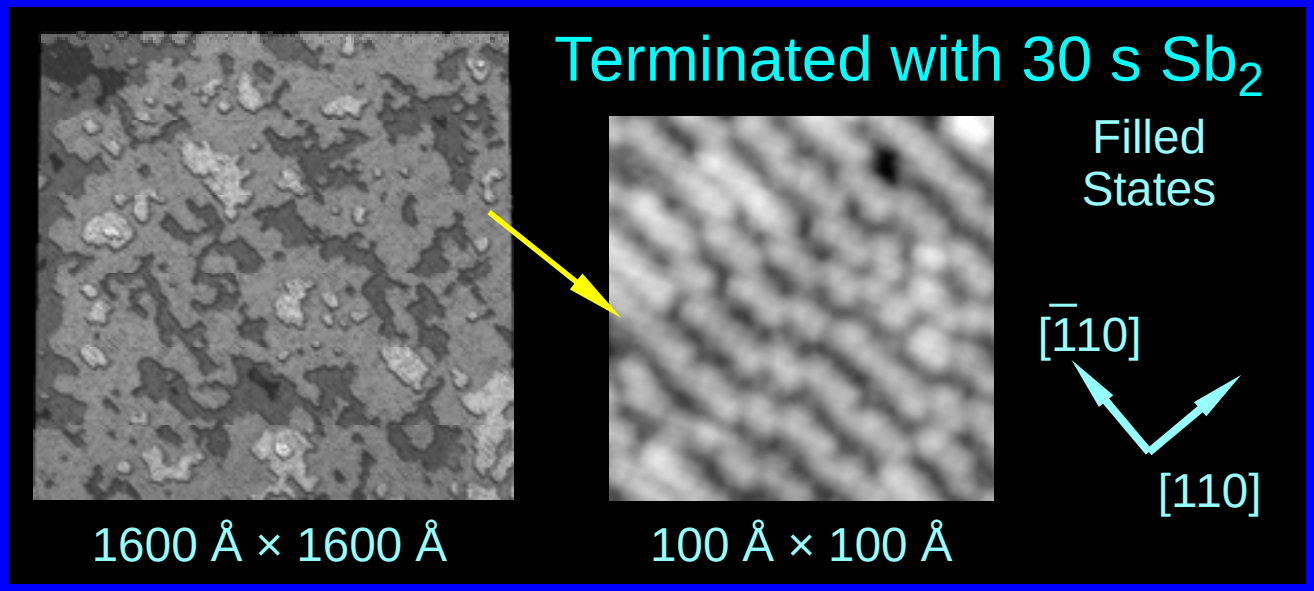
5 min interrupt

5 ML AlSb

1 ML In + Sb_2

~0.5 µm buffer

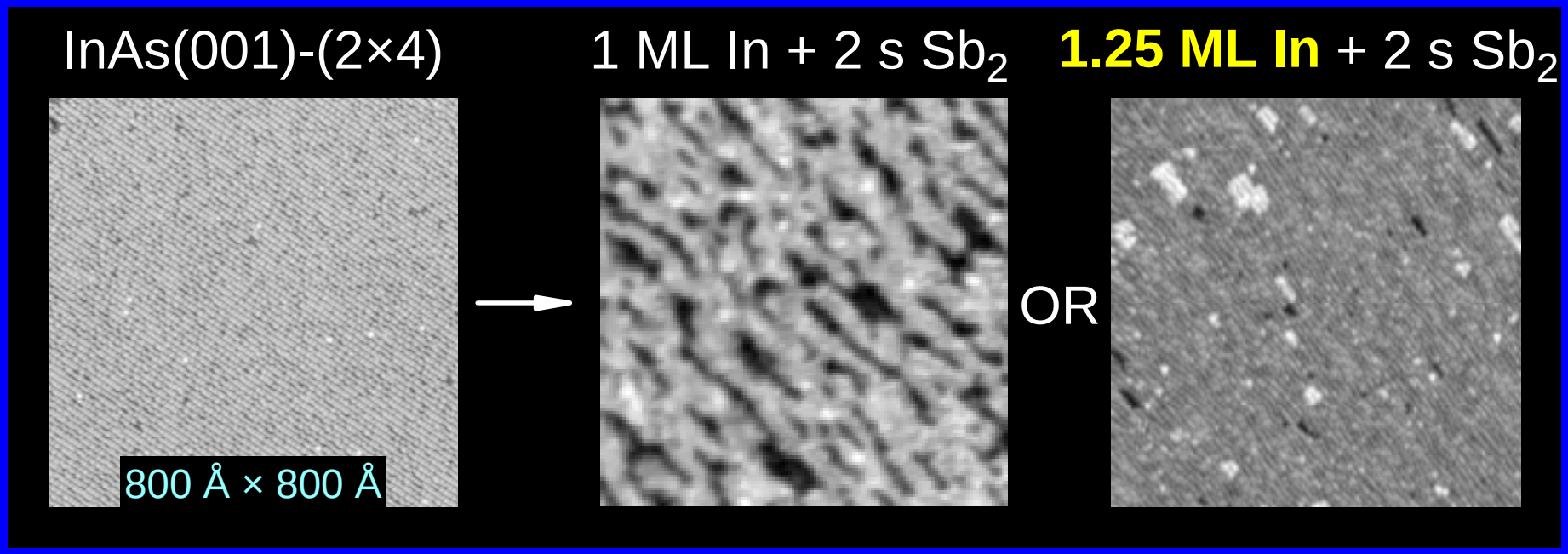
InAs substrate

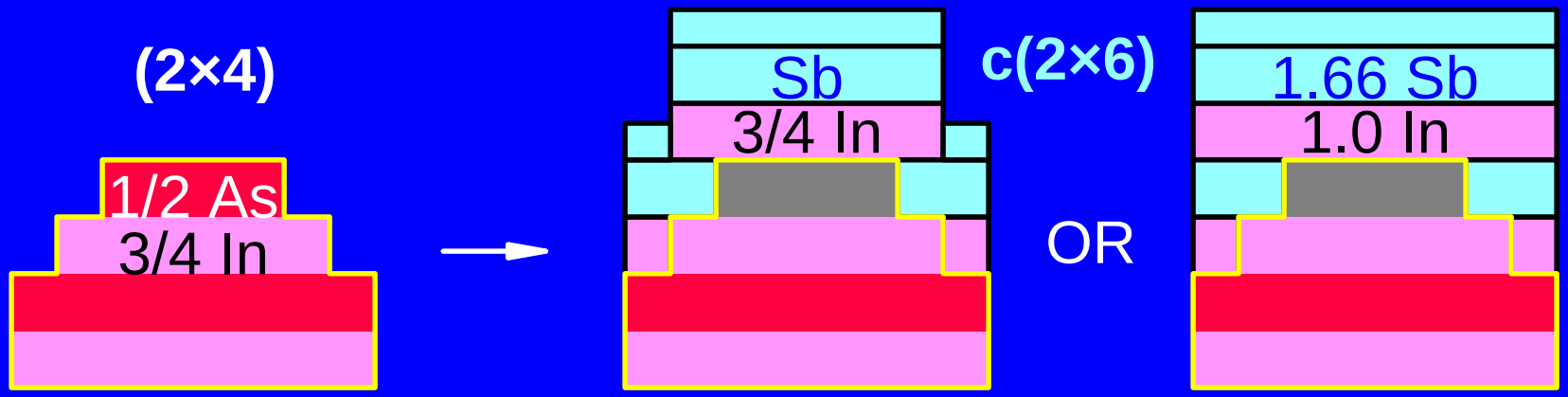


- Represents interface after first barrier
- Now 5 surface levels (but mostly 3)
- Disordered "(1×3)" on surface

Rougher than starting Sb/InAs; caused by lower T?

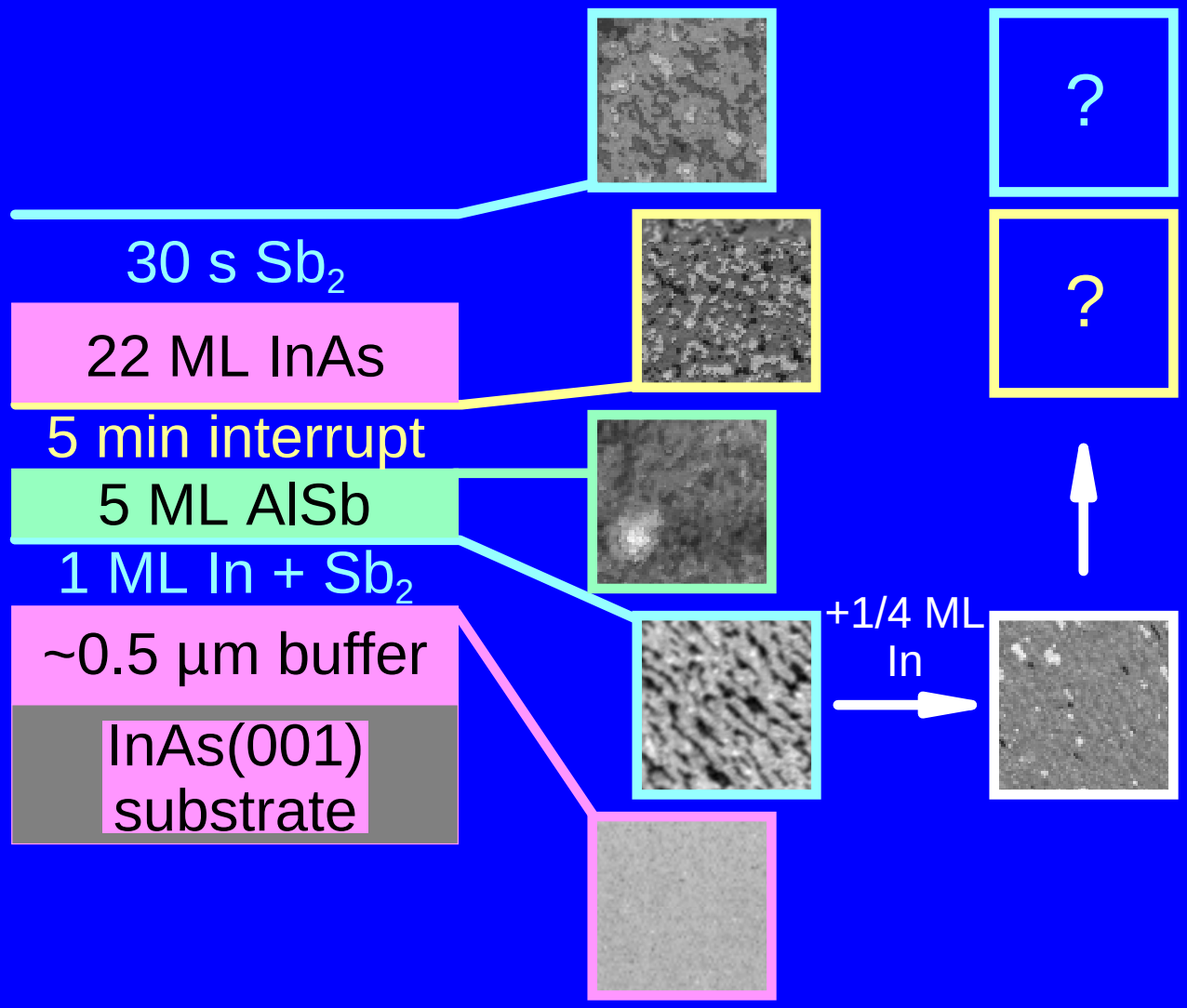
Origins of Interface Roughness: Sb/InAs



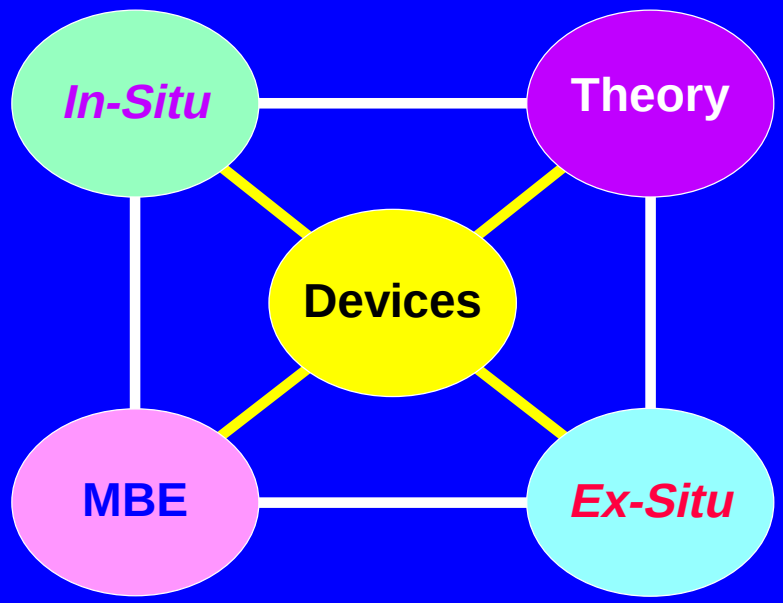


Roughness due to reconstruction stoichiometry.

Evolution of InAs/AlSb/InAs RTD Interfaces



Atomic-scale characterization = atomic-scale control!



MBE Under the Microscope

- Atomic-scale structure ***does*** matter
- Complex interplay between kinetics and thermo.
  - "Obvious" approach does not always improve interface
- Need to better integrate theory, device character.

Work to be done – demonstrate improved devices!